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**(54) MANUFACTURE OF DETECTION PROBE FOR VERY SMALL DISPLACEMENT, DETECTION PROBE FOR VERY SMALL DISPLACEMENT, AND SCANNING PROBE MICROSCOPE AND INFORMATION PROCESSOR USING THESE**

(57)Abstract:

**PURPOSE:** To provide a probe provided with a Fabry-Perot resonator, with which a bright interference fringe of high contrast can be provided.

**CONSTITUTION:** A probe is manufactured by utilizing semiconductor processing technique. A cantilever 4, on which a probe point 6 and an electrode 10 with a gap held for a transparent layer (substrate) 1 is formed on the transparent layer provided with a reflection surface 2 for partially reflecting measurement light 7a on one surface. A reflection surface 4 is formed on the surface of the cantilever 1 opposed to the reflection surface 2.

